

PRODUCT TECHNICAL BRIEF

KYKY 2L-25 Sputter Ion Pump, 22 L/s

KYKY 2L-25 Sputter Ion Pump, 22 L/s - LeakLab solutions for leak testing, vacuum systems and test equipment.

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Technical Data

PARAMETER	PUBLISHED VALUE / INFORMATION
Nominal pumping speed for air	22 L/s
Nominal pumping speed for argon	0.3 L/s
Stated ultimate pressure	7×10^{-8} Pa
Maximum starting pressure	5×10^{-4} Pa
Operating voltage	+7 kV
Inlet flange	DN35CF
Electrode units	1
Maximum bakeout temperature	200 °C with magnets; 300 °C without magnets
Approximate dimensions	222 × 121 × 161 mm
Approximate weight	8 kg

Technical and Project Information

Compact oil-free sputter ion pump for ultra-high-vacuum systems. The 2L-25 provides a nominal air pumping speed of 22 L/s and argon pumping speed of 0.3 L/s, with a DN35CF inlet, +7 kV operating voltage and a stated ultimate pressure of 7×10^{-8} Pa.

KYKY 2L-25 Sputter Ion Pump

The 2L-25 is a compact sputter ion pump for clean, oil-free ultra-high-vacuum systems. With no moving parts in operation, it introduces no mechanical pumping vibration and can maintain pressure in a closed system after suitable roughing and high-vacuum preparation.

Typical applications include surface-analysis instruments, electron microscopy, mass spectrometry, research chambers and other systems where a clean vacuum and low vibration are important.

The pump requires a compatible high-voltage controller and a separate roughing/high-vacuum system to reach the permitted starting pressure. Confirm whether the controller, cable, bakeout hardware and mounting components are included; the source record and current supplier data do not describe the supply scope consistently. Final performance depends on conductance, outgassing, leak tightness, bakeout and the gas load.

Installation and service involve hazardous high voltage, strong magnetic fields and hot surfaces. Use engineered interlocks, grounding and the manufacturer's installation procedure.

- Vacuum Pumps Atmosphere-to-High-Vacuum Dry Pumps High-Vacuum Pumping Stations Ion Pumps Diode Ion Pumps for Heavy Gases Triode Ion Pumps for Noble Gases KYKY RV Rotary-Vane Pumps Roots Booster Pumps Screw Vacuum Pumps Tank Evacuation Systems Turbomolecular Pumps
- Atmosphere-to-High-Vacuum Dry Pumps
- High-Vacuum Pumping Stations
- Ion Pumps Diode Ion Pumps for Heavy Gases Triode Ion Pumps for Noble Gases
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- KYKY RV Rotary-Vane Pumps
- Roots Booster Pumps
- Screw Vacuum Pumps
- Tank Evacuation Systems
- Turbomolecular Pumps
- Helium Reference Leaks
- Scanning Electron Microscopes
- Leak-Detector Accessories

WORLDWIDE PROJECT CONTACT

Send the test object or system, operating conditions, target sensitivity or pressure range, applicable standard, destination country, quantity and schedule. LeakLab will review the project scope.

mail@leaklab.org

Regarding: KYKY 2L-25 Sputter Ion Pump, 22 L/s

Specifications, standards, verification scope, availability and commercial terms must be confirmed for the exact configuration and destination jurisdiction before order or project acceptance.